

	Type	L #	Hits	Search Text	DBs	Time Stamp
1	IS&R	L1	879	("250/310").CCLS.	USPAT	2001/08/17 15:21
2	BRS	L2	125	1 and defect	USPAT	2001/08/17 15:21
3	BRS	L3	36	2 and monitor	USPAT	2001/08/17 15:35
4	BRS	L4	11	2 and classify	USPAT	2001/08/17 15:35

	Comments	Error Definition	Errors
1			0
2			0
3			0
4			0

	U	1 [1]	Document ID	Issue Date	Pages
1	<input type="checkbox"/>	<input checked="" type="checkbox"/>	US 6259960 B1	20010710	119
2	<input type="checkbox"/>	<input checked="" type="checkbox"/>	US 5986263 A	19991116	44
3	<input type="checkbox"/>	<input checked="" type="checkbox"/>	US 5665968 A	19970909	36

	Title	Current OR	Current XRef
1	Part-inspecting system	700/110	250/306 ; 250/310 ; 700/108 ; 700/109
2	Electron beam inspection method and apparatus and semiconductor manufacturing method and its manufacturing line utilizing the same	250/310	250/307
3	Inspecting optical masks with electron beam microscopy	250/310	250/306 ; 250/307

	Retrieval Classif	Inventor	S	C	P	2	3	4	5
1		Inokuchi, Masayuki	<input checked="" type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input checked="" type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>
2		Hiroi, Takashi , et al.	<input checked="" type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>
3		Meisburger, Dan , et al.	<input checked="" type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input checked="" type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>

	U	1	Document ID	Issue Date	Pages
1	<input type="checkbox"/>	<input checked="" type="checkbox"/>	US 6259960 B1	20010710	119
2	<input type="checkbox"/>	<input type="checkbox"/>	US 6259520 B1	20010710	16
3	<input type="checkbox"/>	<input type="checkbox"/>	US 6072574 A	20000606	15
4	<input type="checkbox"/>	<input type="checkbox"/>	US 5659172 A	19970819	15
5	<input type="checkbox"/>	<input type="checkbox"/>	US 5550372 A	19960827	18

	Title	Current OR	Current XRef
1	Part-inspecting system	700/110	250/306 ; 250/310 ; 700/108 ; 700/109
2	Integrated circuit defect review and classification process	356/237.4	250/310 ; 356/237.5 ; 356/394
3	Integrated circuit defect review and classification process	356/237.4	250/310 ; 356/237.5 ; 356/394
4	Reliable defect detection using multiple perspective scanning electron microscope images	250/307	250/310 ; 382/145
5	Apparatus and method for analyzing foreign matter on semiconductor wafers and for controlling the manufacturing process of semiconductor devices	250/310	250/307

	Retrieval Classif	Inventor	S	C	P	2 [1]	3	4	5
1		Inokuchi, Masayuki	<input checked="" type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input checked="" type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>
2		Zeimantz, Lisa R.	<input checked="" type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input checked="" type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>
3		Zeimantz, Lisa R.	<input checked="" type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input checked="" type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>
4		Wagner, Mark , et al.	<input checked="" type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input checked="" type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>
5		Yasue, Takao	<input checked="" type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input checked="" type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>

	U	1	Document ID	Issue Date	Pages
1	<input type="checkbox"/>	<input type="checkbox"/>	US 5777327 A	19980707	9
2	<input type="checkbox"/>	<input checked="" type="checkbox"/>	US 5665968 A	19970909	36

	Title	Current OR	Current XRef
1	Pattern shape inspection apparatus for forming specimen image on display apparatus	250/310	250/306
2	Inspecting optical masks with electron beam microscopy	250/310	250/306 ; 250/307

	Retrieval Classif	Inventor	S	C	P	2	3 [1]	4	5
1		Mizuno, Fumio	<input checked="" type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input checked="" type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>
2		Meisburger, Dan , et al.	<input checked="" type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input checked="" type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>

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3	BRS	L3	36	2 and monitor	USPAT	2001/08/17 15:35
4	BRS	L4	11	2 and classify	USPAT	2001/08/17 15:47
5	BRS	L5	327	1 and (monitor or crt or "cathode ray tube")	USPAT	2001/08/17 15:48
6	BRS	L6	143	5 and images	USPAT	2001/08/17 15:49
7	BRS	L7	37	2 and 6	USPAT	2001/08/17 15:54
8	BRS	L8	12	6 and (joystick or mouse)	USPAT	2001/08/17 15:57

	Comments	Error Definition	Errors
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3			0
4			0
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6			0
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